DIALS: integration

James Parkhurst ECM DIALS workshop August 2015



DIALS: integration

DATA FLOW



Internals: top-level

Tasks in dials.integate:

Calculate the bounding box parameters from strong reflections

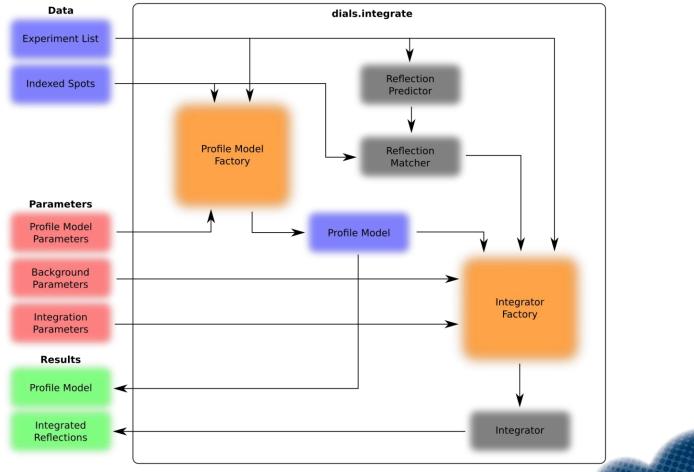
Predict the positions of reflections on the images

Build reference profiles across all images

Integrate the reflections and save output



Internals: top-level





Internals: types of integrator

3D Integrator

Each integration job reads a block of images and extracts reflections into 3D shoeboxes for processing.

Flattened 3D Integrator

Each integration job reads a block of images and extracts 3D shoeboxes which are "flattened" for processing.

<u>2D Integrator</u> Each integration job reads a block of images and extracts partial reflections into 2D shoeboxes for processing.

Single Frame 2D Integrator

Each integration job reads a single image and extracts partials reflections into 2D shoeboxes for processing.

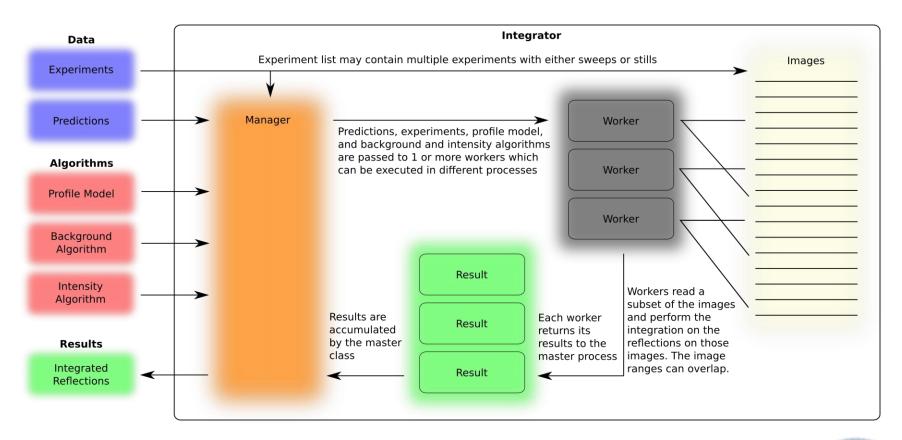
Stills Integrator

Same as the single frame 2d integrator but specialized to accept still experiments rather than rotation experiments.

Integrator



Internals: integrator



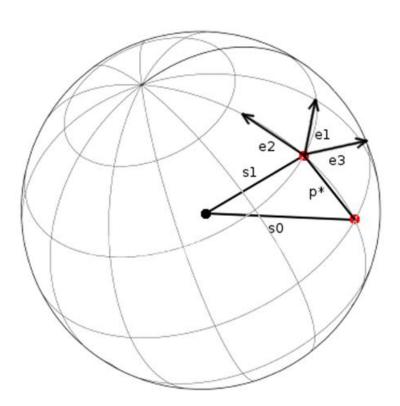


DIALS: integration

REFLECTION SHOEBOXES



Computing reflection shoeboxes



Profile coordinate system

Use the kabsch model of a normal distribution on the surface of the Ewald sphere

$$\exp(\frac{-\epsilon_1^2}{2\sigma_D^2})\exp(\frac{-\epsilon_2^2}{2\sigma_D^2})\exp(\frac{-\epsilon_3^2}{2\sigma_M^2})$$

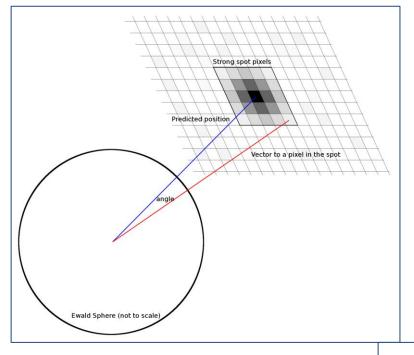
$$e_1 = S_1 \times S_0 / |S_1 \times S_0|$$

$$e_2 = S_1 \times e_1 / |S_1 \times e_1|$$

$$e_3 = (S_1 + S_0) / |S_1 + S_0|$$

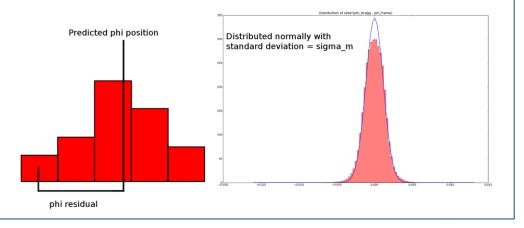


Computing reflection shoeboxes



 σ_D is calculated from the spread of angles between the predicted diffracted beam vector and the vector for each strong pixel in the spot

 σ_M is calculated by maximum likelihood method assuming a normal distribution of phi residuals for each strong pixel in the spot

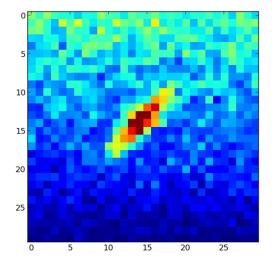


DIALS: integration

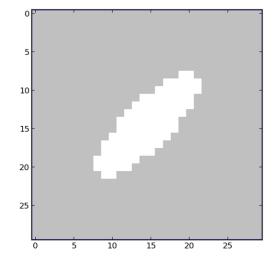
BACKGROUND MODELLING



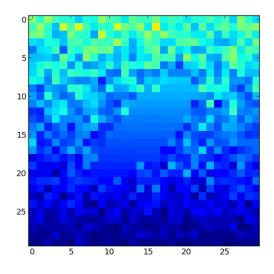
Background determination



Reflection data



Reflection mask



Calculated background



Models

- Options to model the background under the peak as either
 - A constant across each image
 - A constant across all images
 - A plane across each image
 - A hyper-plane across all images
- Computed using simple linear least squares

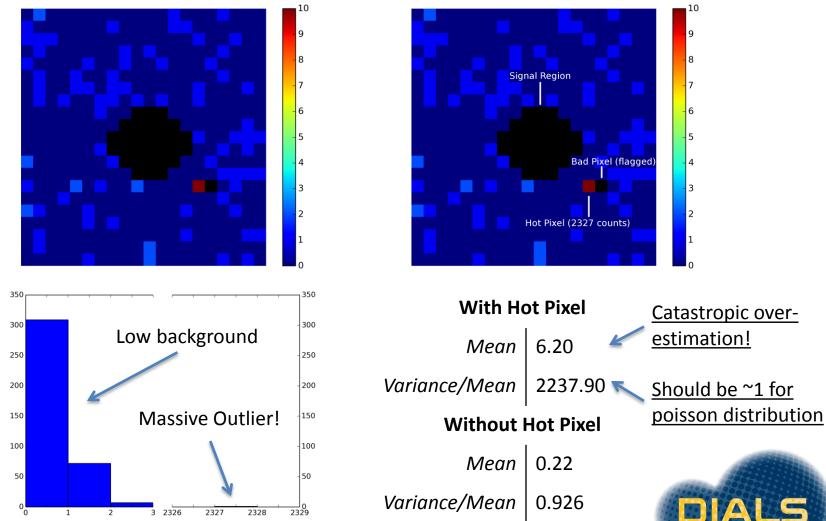


Outliers

- Large valued outliers can cause the background to be over-estimated
- This then causes the reflection intensity to be under-estimated
- Outliers in the background can come from:
 - Intensity from neighbouring spots
 - Hot pixels
 - Zingers
 - Unpredicted reflections
 - Ice rings
 - etc



Outliers

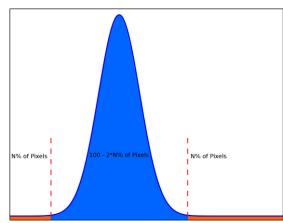


Simple outlier rejection

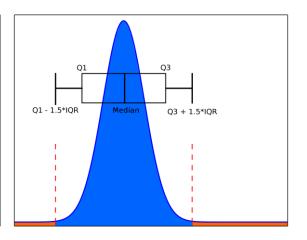
-3 sigma Hean Hean

outlier.algorithm=nsigma

outlier.algorithm=truncated



outlier.algorithm=tukey

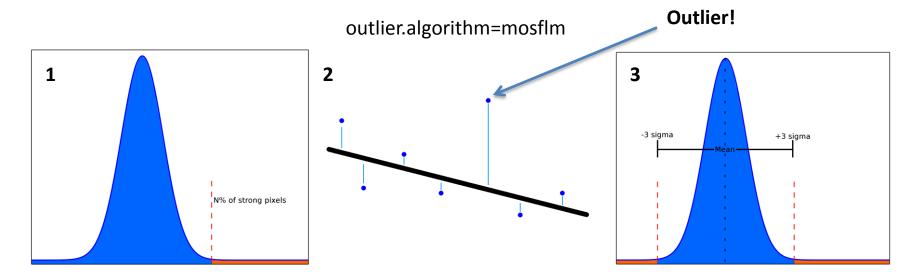


Reject pixels N sigma from the mean

Reject N% of the highest and lowest valued pixels Reject pixels based on the interquartile range



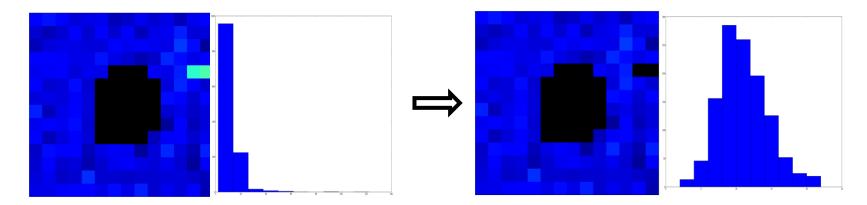
Mosflm-style outlier rejection



Remove N% of strongest pixels and compute the background plane Compute the residuals of all background pixels to the plane Remove pixels whose residuals are greater than N sigma from the plane



XDS-style outlier rejection



Iteratively remove high valued pixels until the distribution of pixel counts resembles a normal distribution



DIALS: integration

SIGNAL INTEGRATION

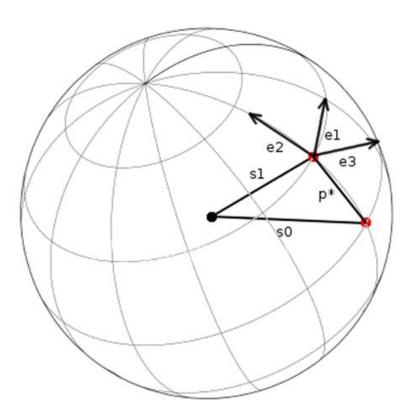


Integration

- Integration algorithm options:
 - Summation
 - 3D profile fitting (as in XDS)
 - 2D profile fitting (future)



3D profile fitting coordinate system



Profile coordinate system

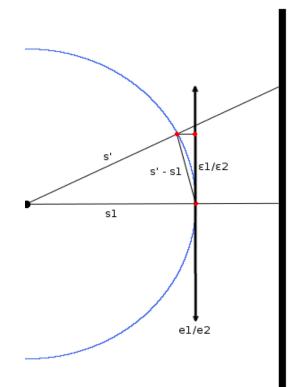
Use Kabsch coordinate system

- Corrects for geometrical distortions
- Makes spots appear to have taken shortest path through Ewald sphere
- Model assumes a Gaussian profile in Kabsch coordinate system

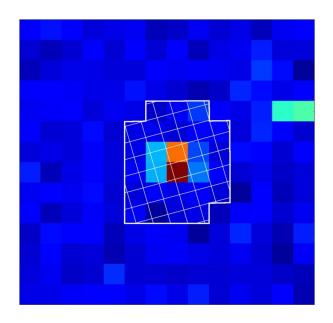
 $e_1 = S_1 \times S_0 / |S_1 \times S_0|$ $e_2 = S_1 \times e_1 / |S_1 \times e_1|$ $e_3 = (S_1 + S_0) / |S_1 + S_0|$



3D profile fitting pixel gridding

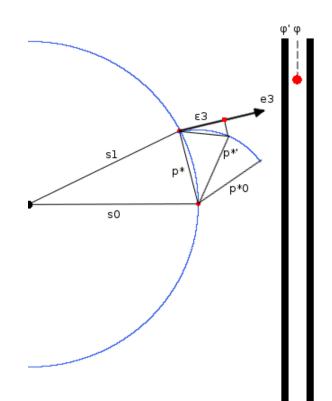


Pixels are mapped to the Ewald sphere

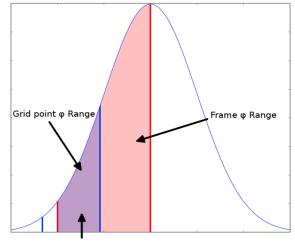


Counts are redistributed to Ewald sphere grid by computing fractional overlap of each pixel and Ewald sphere grid point

3D profile fitting phi gridding



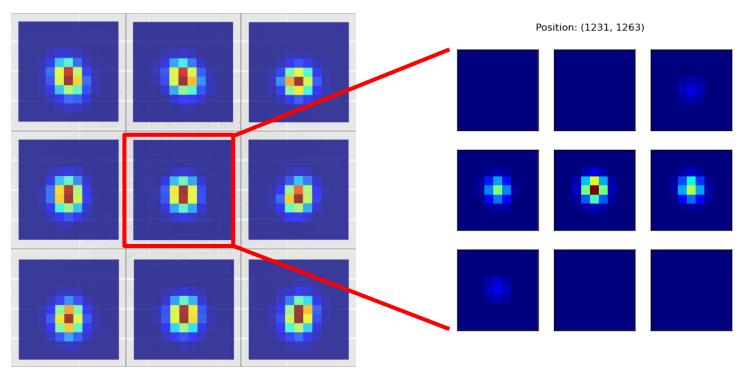
Frames are transformed to make reflection appear as if it took the shortest path through the Ewald sphere



Phi Range Intersection

Counts on each image are distributed by finding the angular overlap between each grid point and each image and integrating over the intersection

Building reference profiles

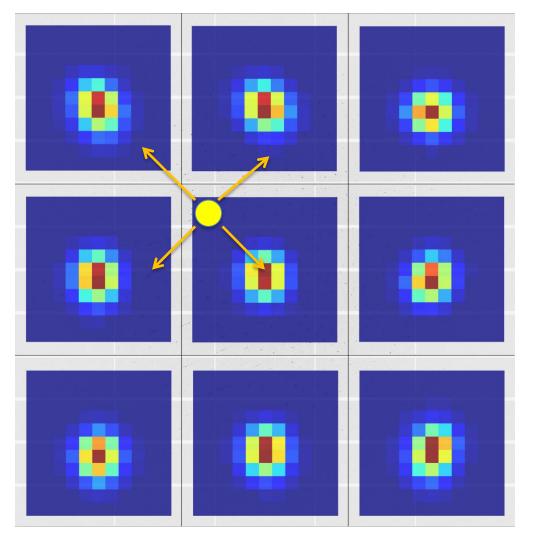


- Reference profiles are formed on a grid covering a given angular range
- Grid options include:
 - Rectangular grid (as in Mosflm)
 - Circular grid (as in XDS)
 - Single reflection (currently for multi-panel detectors)



Building reference profiles

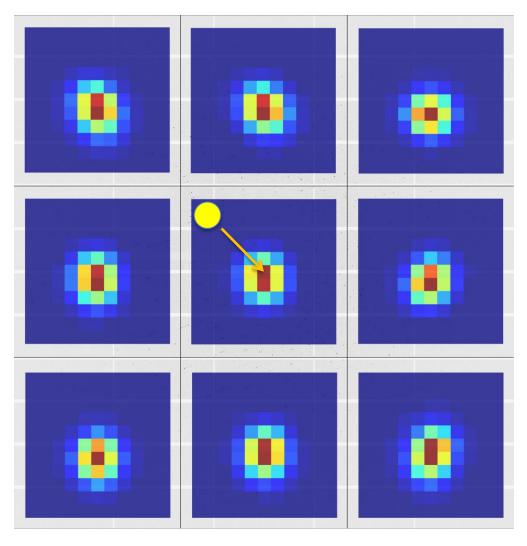
Each strong spot contributes to building the profile at adjacent grid points





Fitting reference profiles

Each reflection is fitted against its closest reference profile





Thanks!

